

Horsley, Publications Last 3 Years

Journal Publications

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- [4] M. Li and **D. A. Horsley**, "Offset Suppression in a Micromachined Lorentz Force Magnetic Sensor by Current Chopping," *Journal of Microelectromechanical Systems*, vol. 23, pp. 1477-1484, Dec 2014.
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Conference Publications

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- [3] M. Li, E. J. Ng, V. A. Hong, C. H. Ahn, Y. Yushi, T. W. Kenny, and **D. A. Horsley**, "Single-structure 3-axis lorentz force magnetometer with sub-30 nT/rt-Hz resolution," in *27th IEEE International Conference on Micro Electro Mechanical Systems (MEMS)*, San Francisco, CA, 2014, pp. 80-83.
- [4] M. Li, V. T. Rouf, S. Sonmezoglu, and **D. A. Horsley**, "Magnetic sensors based on micromechanical oscillators," in *2014 IEEE International Frequency Control Symposium (FCS)*, Taipei, Taiwan, 2014, pp. 1-3.
- [5] M. Li, S. Sonmezoglu, E. J. Ng, V. A. Hong, C. H. Ahn, Y. Yang, T. W. Kenny, and **D. A. Horsley**, "Lorentz force magnetometer with quadrature frequency modulation," in *Solid State Sensors, Actuators and Microsystems Workshop*, Hilton Head, SC, 2014.
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- [17] S. Fung, Y. Lu, H. Y. Tang, J. M. Tsai, M. Daneman, B. E. Boser, and **D. A. Horsley**, "Theory and experimental analysis of scratch resistant coating for ultrasonic fingerprint sensors," in *2015 IEEE International Ultrasonics Symposium (IUS)*, Taipei, Taiwan, 2015, pp. 1-4.
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- [36] P. Taheri-Tehrani, A. D. Challoner, O. Izyumin, B. Boser, and **D. A. Horsley**, "A New Electronic Feedback Compensation Method for Rate Integrating Gyroscopes," presented at the 2016 3rd IEEE International Symposium on Inertial Sensors and Systems, 2016.
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- [39] Y. Kusano, W. Qi, R. Q. Rudy, R. G. Polcawich, and **D. A. Horsley**, "Wideband air-coupled PZT piezoelectric micromachined ultrasonic transducer through DC bias tuning," presented at the 2017 IEEE 30th International Conference on Micro-Electro-Mechanical Systems, 2017.
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- [42] J. Xiaoyue, T. Hao-Yen, L. Yipeng, E. J. Ng, J. M. Tsai, M. J. Daneman, B. E. Boser, and **D. A. Horsley**, "Inter-element coupling effects in pulse-echo ultrasonic fingerprint sensors," presented at the 2017 IEEE 30th International Conference on Micro-Electro-Mechanical Systems, 2017.

Book Chapters

- [1] **D. A. Horsley**, Y. Lu, and O. Rozen, "Flexural Piezoelectric Resonators," in *Piezoelectric MEMS Resonators*, H. Bhugra and G. Piazza, Eds., Springer, 2017.

Patents

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- [1] **D. A. Horsley**. (2016, Dec) WAVE HELLO TO THE NEXT INTERFACE. *IEEE Spectrum*. 46-51. Available: <Go to ISI>://WOS:000391472800012